Abstract

A FORK COVER FOR VERTICAL FURNACE

A semiconductor wafer carrier fork cover to prevent damage to prevent breakage of the semiconductor wafer carrier forks mounted on a robotic semiconductor wafer transfer system during preventative maintenance procedures is described. A semiconductor wafer carrier fork cover has a lower support unit. The lower support unit will fit onto the base of a robotic semiconductor wafer transfer system. An upper covering unit is integrally attached to the lower support unit and will shield the semiconductor wafer carrier forks during preventive maintenance procedures.

(FIGURE 1 IS SUGGESTED FOR PUBLICATION)